

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

OFFICIAL

## Applicant(s):

Crkvcnac et al.

Application No.: 10/734,945

Filed: 12/11/2003

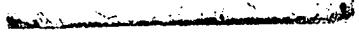
Title: CHEMICAL MECHANICAL POLISHING  
METHOD FOR REDUCING SLURRY  
REFLUX

Attorney Docket No.: 03042US

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JUL 22 2004

Art Unit:

Examiner: PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Before examination, please amend this application as follows: